

What is claimed is:

1. A method of polishing a workpiece in a polishing apparatus, comprising:  
5 conditioning a polishing surface by a contact-type dresser for initial conditioning before starting using said polishing surface;  
polishing a workpiece by bringing said workpiece into contact with said polishing surface after said conditioning; and  
10 dressing said polishing surface after said polishing by a noncontact-type dresser for removing ground-off particles of said workpiece.

2. A method according to claim 1, wherein said noncontact-type dresser and said contact-type dresser are provided in said polishing apparatus.

15 3. A method according to claim 1, wherein said noncontact-type dresser comprises a plurality of fluid jet nozzles for ejecting fluid jets.

4. A method according to claim 3, wherein the pressure of each of said nozzles is variable.

20 5. A method according to claim 1, wherein said contact-type dresser comprises a diamond dresser.

25 6. A method according to claim 1, wherein said polishing surface is dressed by said contact-type dresser before said dressing of said polishing surface by said noncontact-type dresser.

7. A method according to claim 1, wherein said noncontact-type dresser is angularly movable to a standby position located outwardly of said polishing surface.

8. A method according to claim 7, wherein said contact-type dresser is angularly movable to a standby position located outwardly of said polishing surface.

9. A method of polishing workpieces in a polishing apparatus, comprising:  
attaching a member having a polishing surface to a table;  
conditioning said polishing surface by a contact-type dresser for initial conditioning before starting using said polishing surface;

polishing workpieces repeatedly by bringing each of said workpieces into contact with said polishing surface after said conditioning while supplying an abrasive liquid in said polishing; and

10. A method according to claim 9, further comprising holding said each of said workpieces by a vacuum.

11. A method according to claim 9, wherein said noncontact-type dresser comprises a plurality of fluid jet nozzles for ejecting fluid jets.

12. A method according to claim 11, wherein the pressure of each of said nozzles is variable.

13. A method according to claim 9, wherein said contact-type dresser comprises a diamond dresser.

14. A method according to claim 9, wherein said polishing surface is dressed by said contact-type dresser before said dressing of said polishing surface by said noncontact-type dresser.

5           15. A method of polishing a workpiece in a polishing apparatus, comprising:  
attaching a member having a polishing surface to a table;  
conditioning said polishing surface for initial conditioning before starting using said  
polishing surface;  
polishing a workpiece by bringing said workpiece into contact with said polishing  
10 surface after said conditioning; and  
dressing said polishing surface after said polishing for removing ground-off particles  
of said workpiece.